4 – Cassette platforms

2 - Coat Modules

2 - Develop Modules

8 – Hot Plates

9 – Chill Plates

1 – WDS (wash disk system)

A two block system / two robots (not counting carrier station)

Parallel wafer flow processing software option (simultaneous coat & develop) Semifab CD 200+4TEL Temperature & Humidity Unit

Chemical cabinet that contains SMC INR-244-117B Thermocons